

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): F. ISSHIKI, et al

Serial No.: Not yet assigned

Filed: September 25, 2003

For: LASER INTERFEROMETER DISPLACEMENT MEASURING
SYSTEM, EXPOSURE APPARATUS, AND ELECTRON BEAM
LITHOGRAPHY APPARATUS

LETTER CLAIMING RIGHT OF PRIORITY

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

September 25, 2003

Sir:

Under the provisions of 35 USC 119 and 37 CFR 1.55, applicants hereby claim
the right of priority based on:

**Japanese Application No. 2000-089556
Filed: March 28, 2000**

A Certified copy of said application document was filed in parent application
Serial No. 09/818,713, filed March 28, 2001, said certified document filed in the United
States Patent and Trademark Office on July 9, 2001. Acknowledge thereof is
respectfully requested.

Respectfully submitted,



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CIB/jdc
Enclosures
703/312-6600

日本国特許庁
PATENT OFFICE
JAPANESE GOVERNMENT

別紙添付の書類に記載されている事項は下記の出願書類に記載されて
いる事項と同一であることを証明する。
This is to certify that the annexed is a true copy of the following application as filed
with this Office.

出願年月日
Date of Application:

2000年 3月28日

出願番号
Application Number:

特願2000-089556

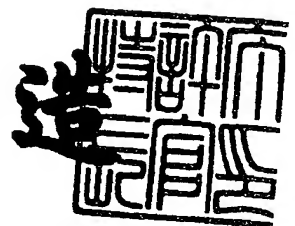
出願人
Applicant(s):

株式会社日立製作所

2001年 4月13日

特許庁長官
Commissioner,
Patent Office

及川耕造



出証番号 出証特2001-303090